

Amendments to the Claims:

This listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A piezoelectric/electrostrictive device made of ~~piezoelectric/electrostrictive film which comprises:~~comprising a substrate section; and an operation section disposed on the substrate section, ~~and constituted of a piezoelectric/ electrostrictive film and an electrode film;~~ said device being capable of operating by displacement of the operation section,

wherein the operation section comprises ~~the~~ piezoelectric/electrostrictive films and electrode films alternately laminated so that uppermost and lowermost layers of the operation section are ~~form the~~ electrode films,

wherein the operation and substrate sections are integrated by firing, ~~and~~

wherein the substrate section comprises a ceramic material ~~is constituted of a~~ ceramics containing a titanium element, and

wherein a content of titanium in the ceramic material within a projected section of the substrate section defined by projecting the electrode film of the lowermost layer of the operation section onto the substrate section is different from the content of titanium in the ceramic material within a non-projected section of the substrate section.

2. (Cancelled)

3. (Currently Amended) The piezoelectric/electrostrictive device made of

~~piezoelectric/electrostrictive film according to claim 21, wherein the content of the titanium element of in the projected section is larger than that of the titanium element of in the non-projected section.~~

4. (Currently Amended) The piezoelectric/electrostrictive device ~~made of piezoelectric/electrostrictive film according to claim 1, wherein the substrate section contains 0.3 to 4% by mass of the titanium element in an equivalent amount of titanium oxide in the projected section projected by the electrode film of the lowermost layer of the operation section.~~

5. (Currently Amended) The piezoelectric/electrostrictive device ~~made of piezoelectric/electrostrictive film according to claim 1, wherein the ceramics constituting ceramic material of the substrate section is~~comprises zirconium oxide.

6. (Currently Amended) The piezoelectric/electrostrictive device ~~made of piezoelectric/electrostrictive film according to claim 1, wherein the substrate section has a thickness of 2 to 10 μm .~~

7. (Currently Amended) The piezoelectric/electrostrictive device ~~made of piezoelectric/electrostrictive film according to claim 1, wherein at least one of the electrode film is constituted of films comprises a material containing platinum which is as a major component.~~

8. (Currently Amended) The piezoelectric/electrostrictive device ~~made of~~
~~piezoelectric/electrostrictive film according to claim 1, wherein at least the electrode~~
~~film is dense in at least that forms the lowermost layer of the operation section is~~
~~dense~~ which contacts the substrate section.

9. (Currently Amended) The piezoelectric/electrostrictive device ~~made of~~
~~piezoelectric/electrostrictive film according to claim 1, wherein the operation section~~
includes two to four layers of the piezoelectric/electrostrictive films.

Claims 10-12 (Cancelled)